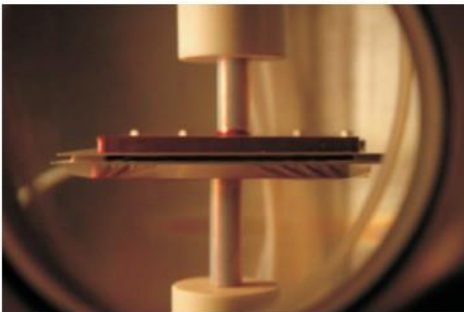


Alban Sublet, CERN - Technology Department - Vacuum, Surfaces and Coatings group

Swiss Plasma Center
Ph.D Plasma Physics



- Dielectric Barrier Discharge



DBD plasma reactor
→ Tetra Pak SiOx barrier film

PECVD Reactor Group
PECVD System Eng.



- Plasma Enhanced Chemical Vapor Deposition



PECVD batch coating system
→ Si thin film solar panels fab

TE-VSC-SCC
Applied Physicist



- Physical Vapor Deposition
- Helicon high density plasma source



PVD of Nb on Cu
→ HIE-ISOLDE SRF cavities



Helicon plasma
→ AWAKE plasma cell R&D

